### Automated inspection of microlens arrays

#### James Mure-Dubois and Heinz Hügli

University of Neuchâtel Institute of Microtechnology, 2000 Neuchâtel, Switzerland

Optical and Digital Image Processing - 07.04.2008





#### Microlens arrays inspection

#### (2) Inspection methods and comparison

- Reference subtraction
- Blob analysis
- Object detection based on blob analysis
- 4 Semi-automated inspection system

### **5** Conclusion





▲ @ ▶ < ∃ ▶</p>

#### Microlens arrays inspection

- Inspection methods and comparison
   Reference subtraction
   Black enclosis
  - Blob analysis
- 3 Defect detection based on blob analysis
- 4 Semi-automated inspection system

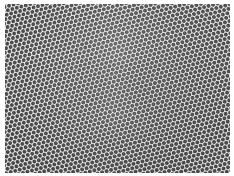
#### 5 Conclusion



A B A B A
 A
 B
 A
 A
 B
 A
 A
 B
 A
 A
 B
 A
 A
 B
 A
 A
 B
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A
 A

## Microlens arrays

- Optical devices combining many small lenses.
- Used for collimation, illumination, imaging[?] ...

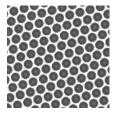


Specificities for this work:

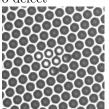
- Small lenses :
  - $10 \leq d \leq 50 \ \mu m.$
- Gaps coated with metal.
- Device with more than 2000000 lenses!



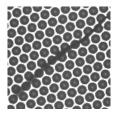
## Inspection - Array defects



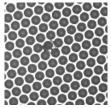
No defect



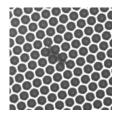
Metal covering



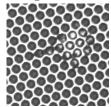
Filament on array



Bad lens



Missing metal

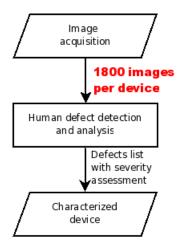


Defects combination





### Semi-automated inspection system



- The number of images to inspect is large.
- Human inspection is slow and reliability is low.
- Most images contain no defects.
- Automated defect detection can speed-up the inspection.



#### Microlens arrays inspection

#### 2 Inspection methods and comparison

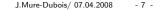
- Reference subtraction
- Blob analysis

#### 3 Defect detection based on blob analysis

4 Semi-automated inspection system

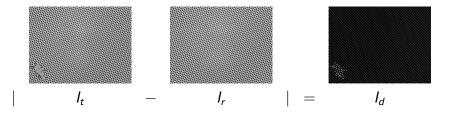
#### 5 Conclusion







## Reference subtraction



#### Advantages :

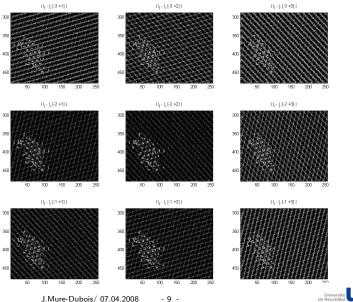
- Short processing time.
- Low memory requirements.

#### **Disadvantages** :

- Requires accurate alignment.
- Sensitive to coarse sampling.



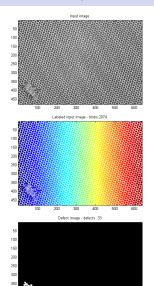
### Alignment and coarse sampling issue



imt

-

### **Blob** analysis



### Advantages :

- Insensitive to alignment and coarse sampling.
- Simple, parametric lens models can be used.
- Easily adapted to new lens array geometry.

### **Disadvantage** :

• Segmentation is critical.



J.Mure-Dubois/ 07.04.2008 - 10 -

Challenge	Reference sub.	Blob anal- ysis
Illumination may vary (gradients + vignetting)	_	0
No alignment between array lattice and image axes		++
Defects may vary greatly in size and intensity characteristics	++	++
Short processing time $(<1s)$	++	+



▲□▶ ▲圖▶ ▲国▶ -

Université de Neuchâtel

#### Microlens arrays inspection

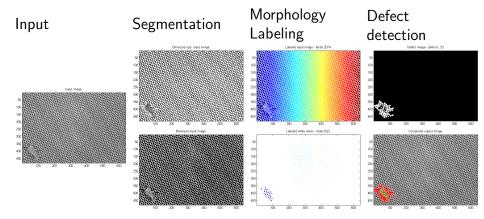
- Inspection methods and comparison
   Reference subtraction
   Blob analysis
- Oefect detection based on blob analysis
  - 4 Semi-automated inspection system

#### 5 Conclusion





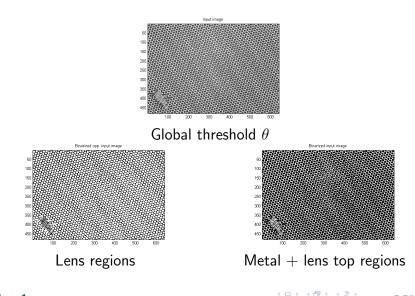
## Blob analysis - Process





A B > A B > A
 B > A
 B > A
 B > A
 B > A
 B > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A
 C > A

## Segmentation

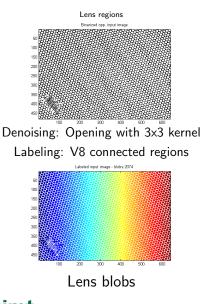


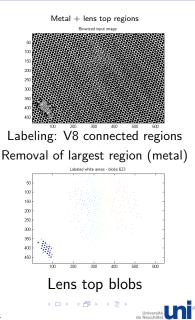


J.Mure-Dubois/ 07.04.2008 - 14

- 14 -

## Morphology and labeling

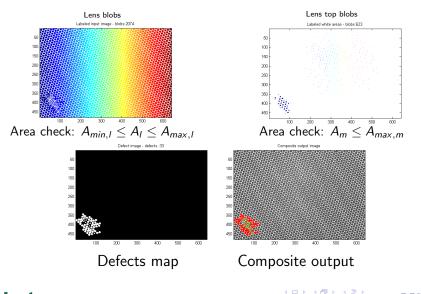




J.Mure-

J.Mure-Dubois/ 07.04.2008 - 15 -

### Blob area analysis





J.Mure-Dubois/ 07.04.2008 - 1

- 16 -

Université

de Neuchâte

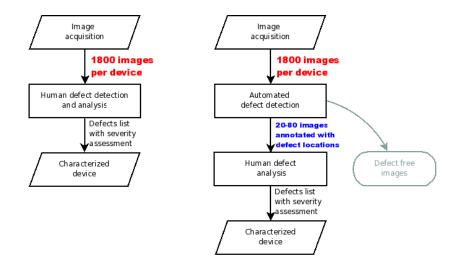
#### Microlens arrays inspection

- Inspection methods and comparison
   Reference subtraction
   Plab applysis
  - Blob analysis
- 3 Defect detection based on blob analysis
- 4 Semi-automated inspection system

### 5 Conclusion



### Semi-automated inspection system





The defect detection module is implemented in Matlab and uses the Image Processing Toolbox.

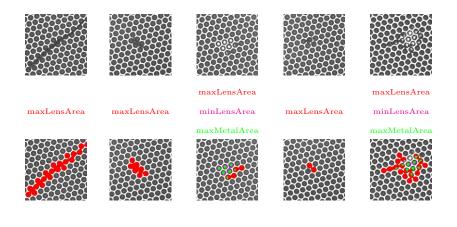
Parameters considered:

- segmentation intensity → segmThr
- lens area  $\rightarrow$ 
  - minArea, maxArea
- maximum *hole* area → maxWhiteArea

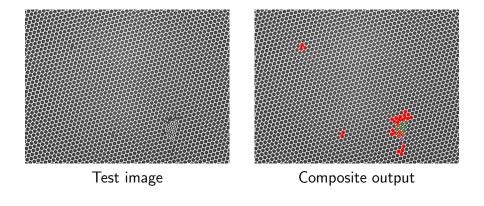
🗟 Edite	or - D:WserskmurejWocumentsWMT\prjV.ensDefectsWatlab\blob_script.m				
Ele Ed	t Iext Gell Tools Debug Desktop Window Help ***				
0 🥔	🖩 X 釉 ඬ 🕫 😁 🎒 🕂 🖯 彩 🗐 釉 副 印刷 Staty Staty 🗤 🛛 🕀 🗆 🕀				
22	· · · · · · · · · · · · · · · · · · ·				
23	23 %% initialize structure which will contain parameters				
24 %% for the worker function (blob MinMax Area.m)					
25 -	5 - paramsBlob.imName = '';				
26 -	26 - paramsBlob.showGraphics = 0; %% DEBUG : display and PAUSE ir				
27 -	7 - paramsBlob.minArea = 065 % minimum area setting				
28 -	8 - paramsBlob.maxArea = 12) %% maximum area setting				
29 -	29 - paramsBlob.segmThr = 120; %% bin. segment. setting				
30					
31 -	paramsBlob.minAreaWhite = 000; %% minimum area setting				
32 - paramsBlob.maxAreaWhite = 013;) %% maximum area setting					
	K				
🗄 blob_script.m 🗏 caption_blobscript_disp.m 🗏 blob_MinMax_Area_MinThorough.m 🗵					
	blob_script Ln 26 Col 37 OVR				



### Blob area - Defect detection



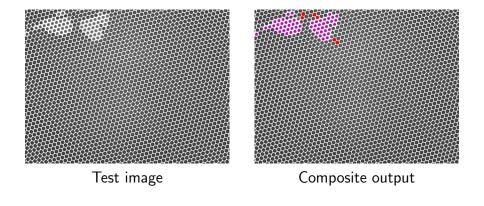






J.Mure-Dubois/ 07.04.2008

イロト イヨト イヨト・

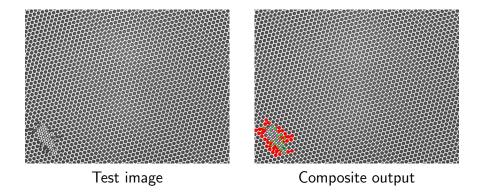




J.Mure-Dubois/ 07.04.2008 - 22

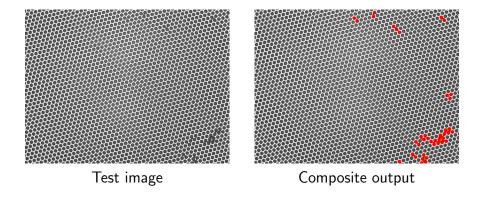








イロト イヨト イヨト・





J.Mure-Dubois/ 07.04.2008 - 24

・ロト ・ 日下 ・ モート

Tests carried out on devices with a high number of defects.

Device	А	В
Images acquired	1804	1804
Defect detected automatically	446	242
Independent human annotation		
Defects found	133	58
False positive rate	17.4%	10.2%
False negative rate	0%	0%
Semi-automated human annotation		
Defects found	433	242
False positive rate	0.72%	0%
False negative rate	0%	0%



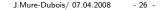
▲□▶ ▲圖▶ ▲≣▶ ○

#### Microlens arrays inspection

- Inspection methods and comparison
   Reference subtraction
   Plab analysis
  - Blob analysis
- 3 Defect detection based on blob analysis
- 4 Semi-automated inspection system

### 5 Conclusion



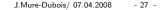




## Conclusions

- Image processing methods enabling automation of microlens arrays inspection were studied
- An automated **defect detection** system was realized, based on a blob analysis method
- Tests confirm that no defect goes through the system.
- Tests show a low false positive rate: the human supervisor is freed from the burden of watching large series of defect free images.
- Possible improvements:
  - Automatic parameter generation from reference images
  - Smarter segmentation methods (gradient based)







The authors would like to thank B. Putz and K. Weible at SUSS MicroOptics, for providing the annotated test image databases

# Thank you for your attention !





A B > A B >

P. Nussbaumy, R. Voelkel, H.-P. Herzig, M. Eisner, and S. Haselbeck.

Design, fabrication and testing of microlens arrays for sensors and microsystems.

Pure Appl. Opt., 6:617-636, 1997.



A B > A B >